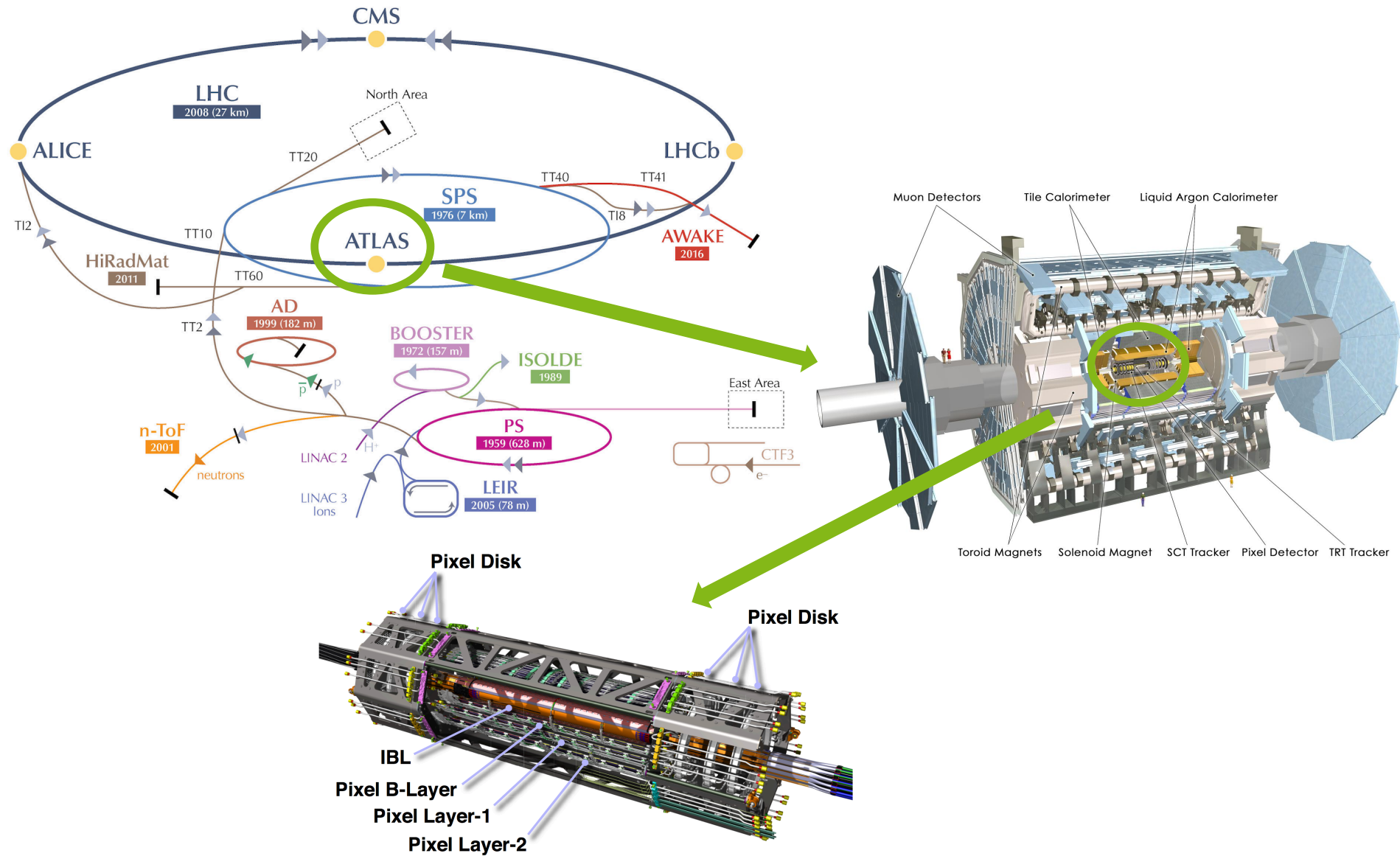


Improvement of planar silicon Pixel Sensors for the ATLAS ITk upgrade

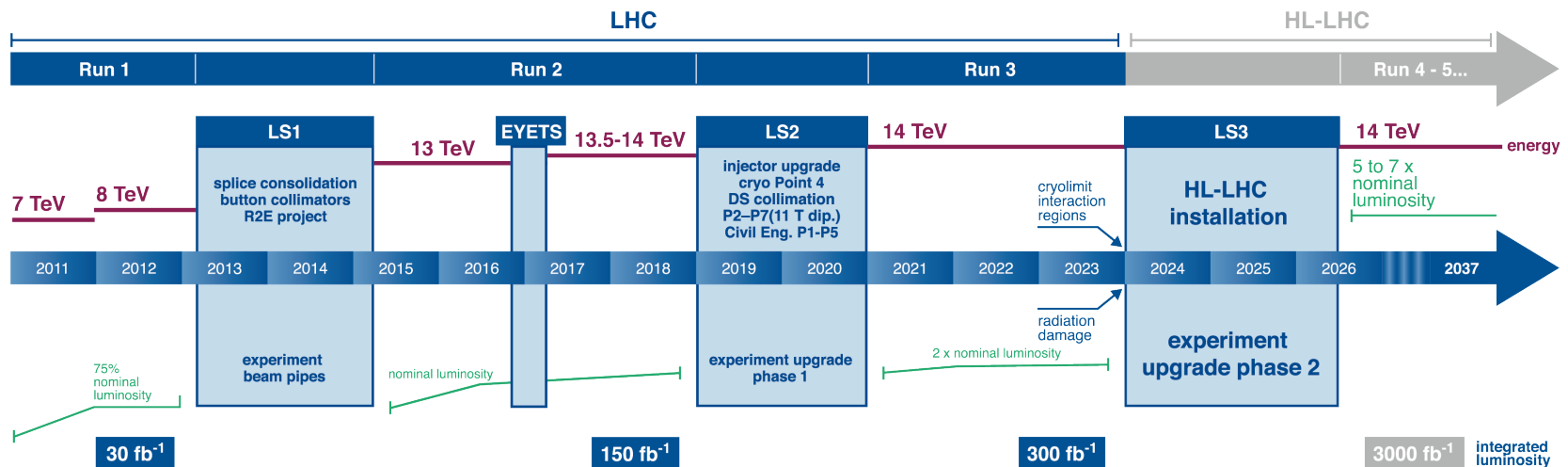
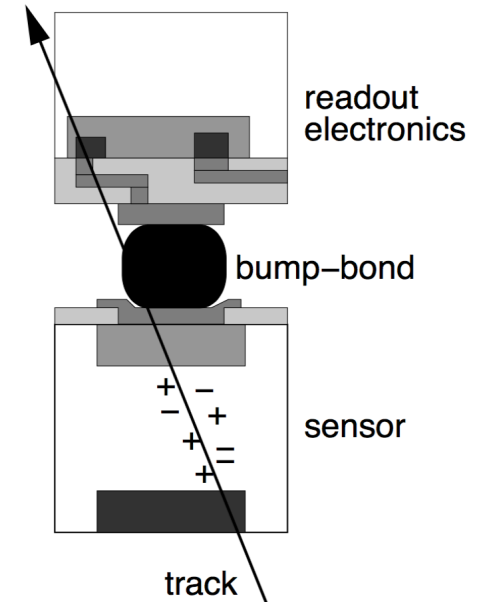
BCD School Cargèse, April 5th 2017

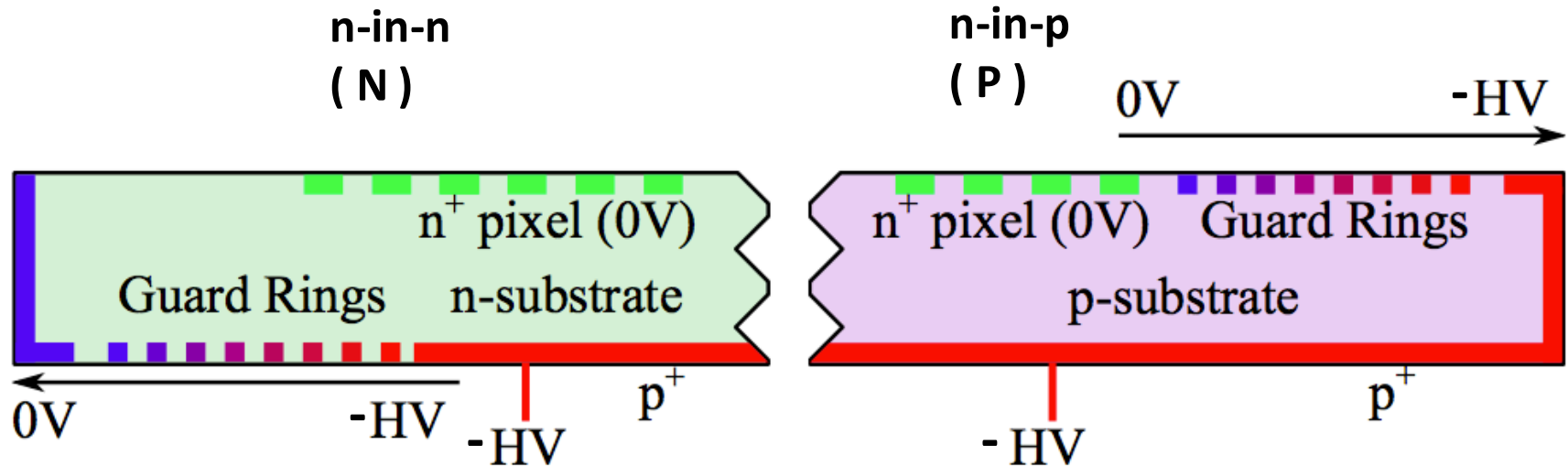
Sascha Dungs

TU Dortmund, Experimentelle Physik IV



- currently the pixel detector consists of hybrid modules with n-in-n type pixel sensors
- for the phase 2 upgrade the inner detector will be replaced completely
- final layout is not set yet, but well-established hybrid concept is preferred
- n-in-p type pixel sensors could be a possible cost-effective alternative for n-in-n sensors





- n-type substrate
- front side: n⁺-implants (→ pixels)
- back side : p⁺-implants
- Guard Rings for defined potential drop
- GR on p-side
- two side processing
- p-type substrate
- GR on n-side
- one side processing

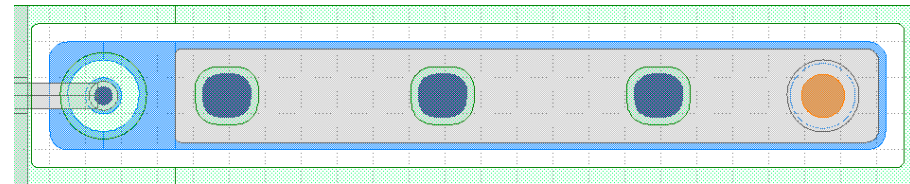
Design of new n-in-p sensors:

- efficiency improvements
- material reduction
- same design to compare the types
- new FE-Chip -> pixel size 50x50 μm^2

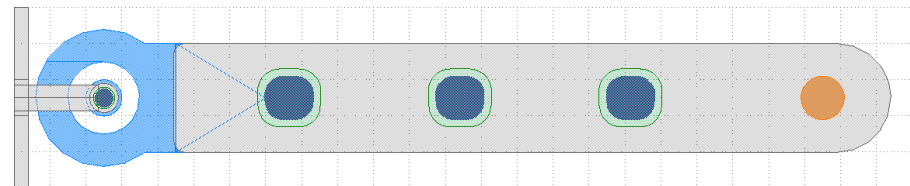
Comparing measurements:

- IV and CV characterizations are done
- further measurements follow, e.g. hit efficiency

Standard n-in-n IBL pixel design (250x50 μm^2)



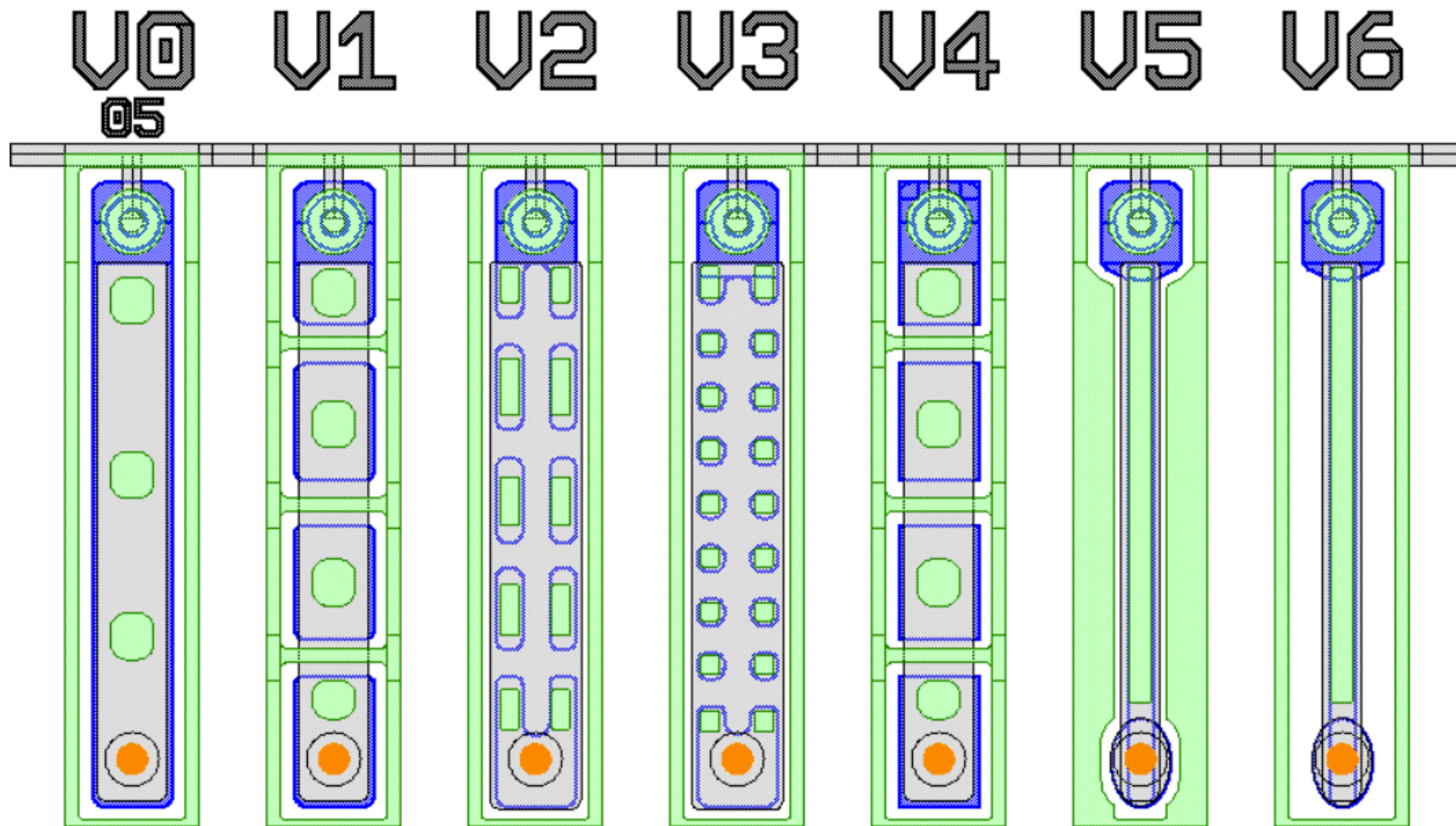
Example for equivalent n-in-p pixel design

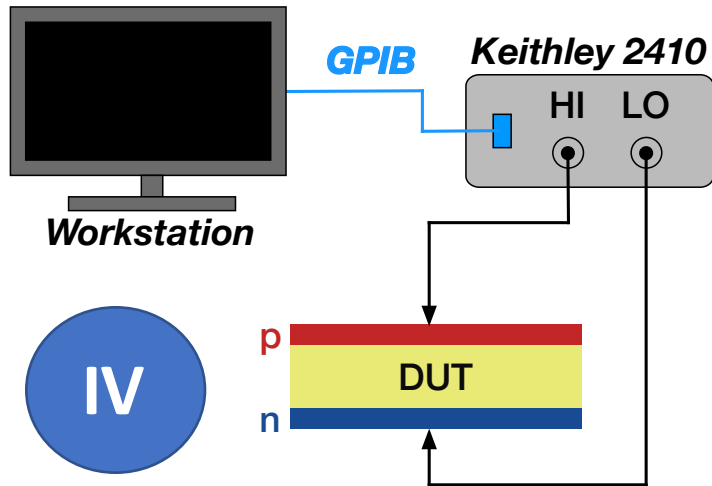


	D-01	D-02	M-01	M-02	M-03
manufacture	CIS	CIS	HLL	HLL	CIS
type	n-in-n	n-in-n	n-in-p	n-in-p	n-in-p
thickness [μm]	200	200	150	150	100

Thank you for your attention!

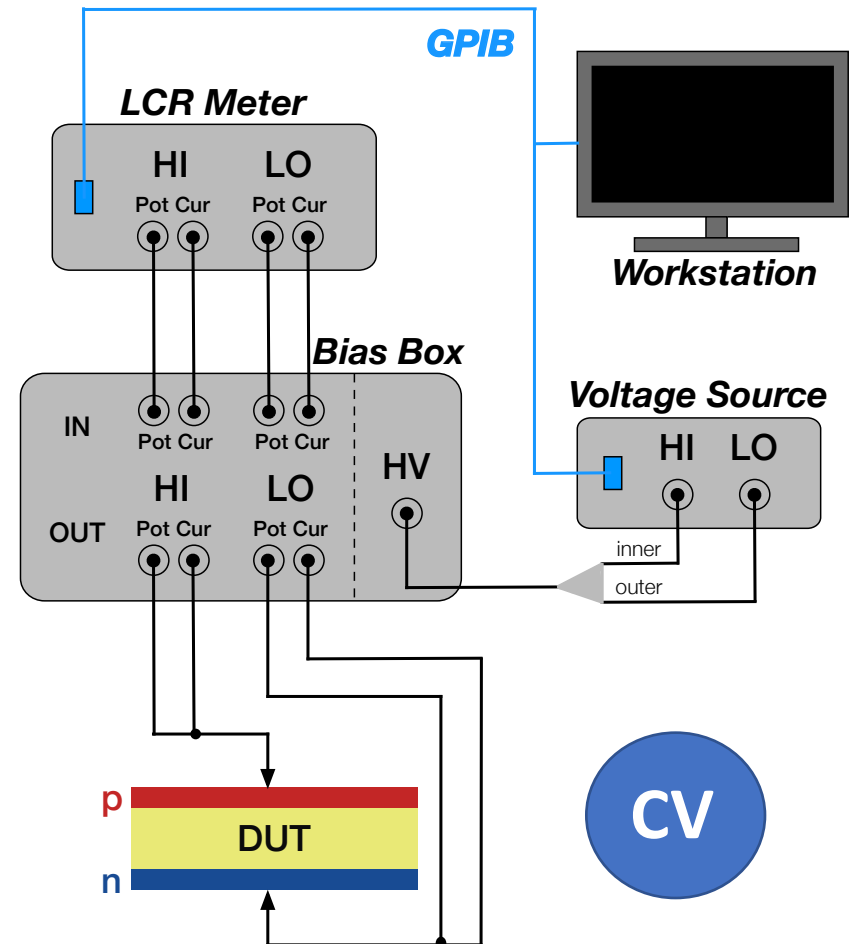
Backup





Criteria for good sensor:

- thickness $\leq 200\mu\text{m}$
- leakage current:
 - $I_{\text{total}} \leq 0.75\mu\text{A}/\text{cm}^2$ at 20°C
 $\Rightarrow I_{\text{max}} \approx 2.5\mu\text{A}$
 - measured at $V_{\text{depl}} + 50\text{ V}$



	RD53	<i>FE-I4</i>
technology	65 nm	130 nm
Pixel dimension	50 μm x 50 μm	50 μm x 250 μm
# of pixels	~140 000	26880
chip dimension	18 mm x 20 mm	19 mm x 20 mm
hit rate	3 GHz/cm ²	0.4 GHz/cm ²
in-time threshold	< 1000 e	< 4000 e
typ. noise (ENC)	< 100 e	< 300 e
bandwidth	5 Gb/s	160 Mb/s
rad. hardness	> 5 MGy	> 2.5 MGy